

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Date February 11, 2009

In re the Application of

Hideki SATO

Application No.: 10/594,458

Filed: September 26, 2006

For: METHOD FOR EVALUATING CRYSTAL DEFECTS OF SILICON WAFER



Group Art Unit: 1792

Examiner: L. VINH

Docket No.: 129546

**LARGE ENTITY PETITION FOR 1st - 3rd EXTENSION
OF TIME UNDER 37 C.F.R. §1.136(a) AND
TRANSMITTAL OF FEE UNDER 37 C.F.R. §1.17**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Transmitted herewith is a response to the outstanding Official Action in the above-identified patent application. The shortened statutory period having expired December 15, 2008, an extension of time for a period of two months is hereby requested. Attached hereto is our Check No. 215097 in the amount of \$490 in payment for:

<u> </u>	Extension fee for response within first month pursuant to §1.136(a) (\$130.00)
<u> X </u>	Extension fee for response within second month pursuant to §1.136(a) (\$490.00)
<u> </u>	Extension fee for response within third or subsequent month pursuant to §1.136(a) (\$1,110.00)

The Commissioner is hereby authorized to charge any additional fee or credit any overpayment associated with this communication to Deposit Account No. 15-0461.

Respectfully submitted,

William P. Berridge
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WPB:NAB/kjl

02 FC:1252

490.00 OP

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DEPOSIT ACCOUNT USE
AUTHORIZATION
Please grant any extension
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